

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Venkat Selvamanickam

Title: METALORGANIC CHEMICAL VAPOR DEPOSITION (MOCVD)
PROCESS AND APPARATUS TO PRODUCE MULTI-LAYER HIGH-
TEMPERATURE SUPERCONDUCTING (HTS) COATED TAPE

App. No.: 10/602,468

Filed: June 23, 2003

Examiner: Aaron Austin

Group Art Unit: 1784

Att. Dkt. No.: 1014-SP156-US

Confirmation No.: 2661

Mail Stop AMENDMENT
Commissioner for Patents
PO Box 1450
Alexandria, VA 22313-1450

REPLY TO FINAL OFFICE ACTION

Dear Commissioner:

In response to the Final Office Action mailed July 21, 2011, please amend the above-identified application as follows:

Claim Amendments begin on page 2.

Remarks begin on page 5.